

2016 International Workshop on EUV Lithography (2016 EUVL Workshop)

June 13-16, 2016 ■ CXRO ■ LBL ■ Berkeley, CA

Thursday, June 16, 2016



www.euvlitho.com

2016 EUVL Workshop

Organized by



Promoting EUV Lithography via
Workshops, Consulting and Education

with support from

EUREKA



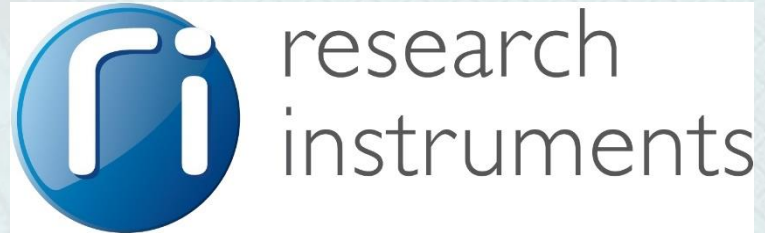
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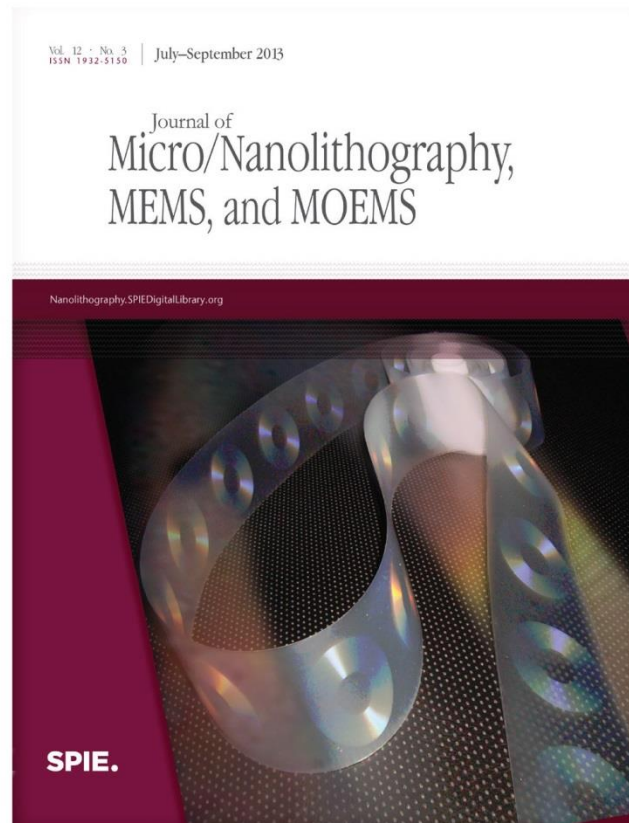
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SPIE

Submit your work to the *Journal of Micro/Nanolithography, MEMS, and MOEMS*



2016 EUVL Workshop Survey

To be given out in the afternoon break

- When do you expect to see the insertion of EUVL in HVM, at which node and for how many critical layers?
- What do you see as top three challenges for insertion of EUVL in HVM?
- What topic (s) /presentations (s) you found most valuable in this year's workshop agenda?
 - Please list top three.
- Which topics / speakers you will like to have in the 2016 EUVL Workshop agenda?
- Any additional Feedback

Announcements

- **Workshop Proceedings**
- PDF version of presentations will be published in the proceedings by July 15th.
- If you have not submitted a PDF version of your presentation, we will make a PDF for you it. If you have animation, please make your own PDF.
- If you need to make changes to your presentation, please send me revised version no later than end of next week (June 24th)

WORKSHOP AGENDA

- **8:40 AM ...Session 5: Keynote Presentations**
- **9:20 AM..... Session 6: Mask 1**
- **10:00 AMBreak (20 Minutes)**
- **10:20.....Session 7: Mask 2**
- **11:30.....Lunch**
Steering committee meeting (Closed)

WORKSHOP AGENDA

- **2:10 PMBreak (20 Minutes)**
- **2:30 PM.....Session 9-10: EUV Resists**
- **4:50 PM Workshop Survey (ALL)**
- **5:00 PMWorkshop Summary**
- **6:00 PMSession 11: Poster Session
(60 Minutes)**
- **7:30 PM.....Dinner (Hotel Claremont)**